

## Photoderivatization of the Surface of Luminescent Porous Silicon with Formic Acid

Eric J. Lee, James S. Ha, and Michael J. Sailor\*

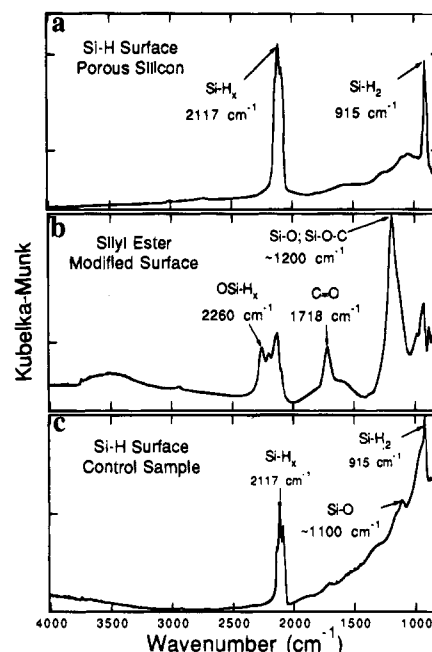
Department of Chemistry and Biochemistry  
University of California, San Diego  
San Diego, California 92093-0358

Received May 15, 1995

Modification of technologically important surfaces is currently an active field of research. Important examples include silyl halides on  $\text{SiO}_2$ ,<sup>1</sup> carboxylic acids on metal oxides,<sup>2</sup> thiols on  $\text{Au}^3$  or  $\text{GaAs}$ ,<sup>4</sup> organophosphates on oxides,<sup>5</sup> and recently, alkanes on  $\text{Si}$ .<sup>6</sup> In this work, we report a new reaction scheme for functionalizing  $\text{Si}$  surfaces by light-induced reactions. The  $\text{Si}$  used in this report was etched in  $\text{HF}$  to prepare a porous layer several microns deep.<sup>7</sup> The advantage of using porous  $\text{Si}$  is that it has a very large surface area which greatly aids spectroscopic identification of surface composition. Furthermore, the visible photoluminescence of porous  $\text{Si}$  is sensitive to physisorbed and chemisorbed species, allowing for an additional probe of the chemical nature of the surface.

The  $\text{Si}$  porous layer was made by anodically etching n-type  $\text{Si}(100)$  ( $0.03\text{--}0.05\ \Omega\text{-cm}$ ) with 1:1 49%  $\text{HF}$ (aqueous)/ $\text{CH}_3\text{-CH}_2\text{OH}$  in a Teflon etch cell. The counter electrode was a coiled Pt wire. The etch conditions were  $100\ \text{mA}/\text{cm}^2$  for 2–3 min under  $15\ \text{mW}/\text{cm}^2$  white light from a tungsten filament source. After etching, the samples were washed with  $\text{CH}_2\text{Cl}_2$  and thoroughly dried under a  $\text{N}_2$  stream. The resulting surface is hydride terminated. Diffuse reflectance Fourier-transform infrared spectroscopy (DRIFTS) identified strong absorptions assigned to  $\text{Si-H}_x$  stretches around  $2100\ \text{cm}^{-1}$  and a  $\text{Si-H}_2$  scissor mode at  $915\ \text{cm}^{-1}$ , Figure 1a.<sup>8</sup>

The porous  $\text{Si}$  samples were derivatized in neat  $\text{HCOOH}$  containing 1 M  $\text{HCOONa}$  in the same Teflon container used for the  $\text{HF}$  etch. A bias of  $+0.3\ \text{V}$  was applied to the  $\text{Si}$  working electrode relative to the Pt counter electrode ( $\text{Si}$  reverse-biased), in the presence of white light to generate a photocurrent of 2–3  $\text{mA}/\text{cm}^2$ . The photocurrent dropped to half its initial value over



**Figure 1.** Diffuse reflectance FTIR spectra of porous  $\text{Si}$  surfaces: (a) as-formed ( $\text{HF}$  etched) porous  $\text{Si}$  showing strong  $\text{Si-H}_x$  absorptions; (b) ester-modified surface; (c) sample treated identically to that in panel b but without illumination; this spectrum shows little or no evidence of silyl esters.

a period of several minutes. A small amount of gas was evolved, indicating that the current may be due to decomposition of the acid by a Kolbe-type reaction.<sup>9</sup> After 10 min the sample was removed and washed with formic acid and  $\text{CH}_2\text{Cl}_2$ . The sample was then dried under a  $\text{N}_2$  stream and placed under vacuum.

The resulting derivatized surface was identified by DRIFTS, Figure 1b. The surface silyl ester is identified by the  $\nu(\text{CO})$  stretching vibration at  $1716 \pm 2\ \text{cm}^{-1}$ . By comparison, the carbonyl  $\text{C-O}$  stretch of free formic acid occurs at  $1720\ \text{cm}^{-1}$ , and molecular silyl esters have  $\nu(\text{CO})$  in the  $1700\text{--}1770\ \text{cm}^{-1}$  region (for example,  $\nu(\text{CO})$  of  $(\text{CH}_3\text{CH}_2)_3\text{SiOOCCH}_3$  occurs at  $1720\ \text{cm}^{-1}$ ).<sup>10</sup> The  $\text{Si}$  is oxidized, as identified by a broad band around  $1200\ \text{cm}^{-1}$ , assigned to  $\text{Si-O}$  stretching and  $\text{Si-O-C}$  bending vibrations. An additional  $\text{Si-H}_x$  stretching mode is observed at  $2260\ \text{cm}^{-1}$ , assigned to  $\nu(\text{Si-H})$  from  $\text{Si}$  bonded to the formate ester. This frequency is slightly higher than the value of  $\nu(\text{Si-H})$  typically observed on oxidized  $\text{Si}$  ( $2254\ \text{cm}^{-1}$ ),<sup>8</sup> as expected from the greater inductive ability of the ester,<sup>10</sup> and is an indication that the back-bonded  $\text{O}$  is associated with the surface-bound ester species, though some surface oxide may be present as well. The absorptions assigned to the silyl ester persist after exposure to vacuum and thorough washing with alcohols,  $\text{H}_2\text{O}$  and  $\text{CH}_2\text{Cl}_2$ , although the signals disappear slowly upon soaking in water or alcohol for several hours. Molecular silyl esters are known to transesterify upon exposure to alcohols or  $\text{H}_2\text{O}$ .<sup>11</sup>

A reference sample was prepared by treating porous  $\text{Si}$  under identical conditions with the exception that it was not exposed to light. The current in the dark was  $<0.05\ \text{mA}/\text{cm}^2$ . This sample showed no sign of ester formation, possessing only the  $\text{Si-H}$  stretching vibrations of the starting porous  $\text{Si}$ , Figure 1c.

(9) (a) Bard, A. J. *Science* **1980**, *207*, 139. (b) March, J. *Advanced Organic Chemistry*, 4th ed.; Wiley and Sons: New York, 1992; pp 729–732.

(10) Anderson, D. R. In *Analysis of Silicones*; Smith, A. L., Ed.; J. Wiley and Sons: New York, 1974; pp 247–286.

(11) (a) Eaborn, C. *Organosilicon Compounds*; Academic Press: New York, 1960; p 316. (b) Pawlenko, S. *Organosilicon Chemistry*; Walter de Gruyter: Berlin, 1986; p 53.

\* Author to whom correspondence should be addressed.

(1) (a) Dulcey, C. S.; Georger, J. H., Jr.; Krauthamer, V.; Stenger, D. A.; Fare, T. L.; Calvert, J. M. *Science* **1991**, *252*, 551. (b) Sagiv, J. *J. Am. Chem. Soc.* **1980**, *102*, 92. (c) Murray, R. W. *Acc. Chem. Res.* **1980**, *13*, 135. (d) Bolts, J. M.; Bocarsly, A. B.; Palazzotto, M. C.; Walton, E. G.; Lewis, N. S.; Wrighton, M. S. *J. Am. Chem. Soc.* **1979**, *101*, 1378.

(2) (a) Allara, D. L.; Nuzzo, R. G. *Langmuir* **1985**, *1*, 45. (b) Crowell, J. E.; Chen, J. G.; Yates, J. T. *J. Chem. Phys.* **1986**, *85*, 3111. (c) Laibinis, P. E.; Hickman, J. J.; Wrighton, M. S.; Whitesides, G. M. *Science* **1989**, *245*, 845. (d) Meyer, T. J.; Meyer, G. J.; Pfennig, B. W.; Schoonover, J. R.; Timpson, C. J.; Wall, J. F.; Kobusch, C.; Chen, X.; Peek, B. M.; Wall, C. G.; Ou, W.; Erickson, B. W.; Bignozzi, C. A. *Inorg. Chem.* **1994**, *33*, 3952.

(3) (a) Nuzzo, R. G.; Fusco, F. A.; Allara, D. L. *J. Am. Chem. Soc.* **1987**, *109*, 2358. (b) Chidsey, C. E. D.; Loiacono, D. N. *Langmuir* **1990**, *6*, 682. (c) Bain, C. D.; Troughton, E. B.; Tao, Y. T.; Evall, J.; Whitesides, G. M.; Nuzzo, R. G. *J. Am. Chem. Soc.* **1989**, *111*, 321.

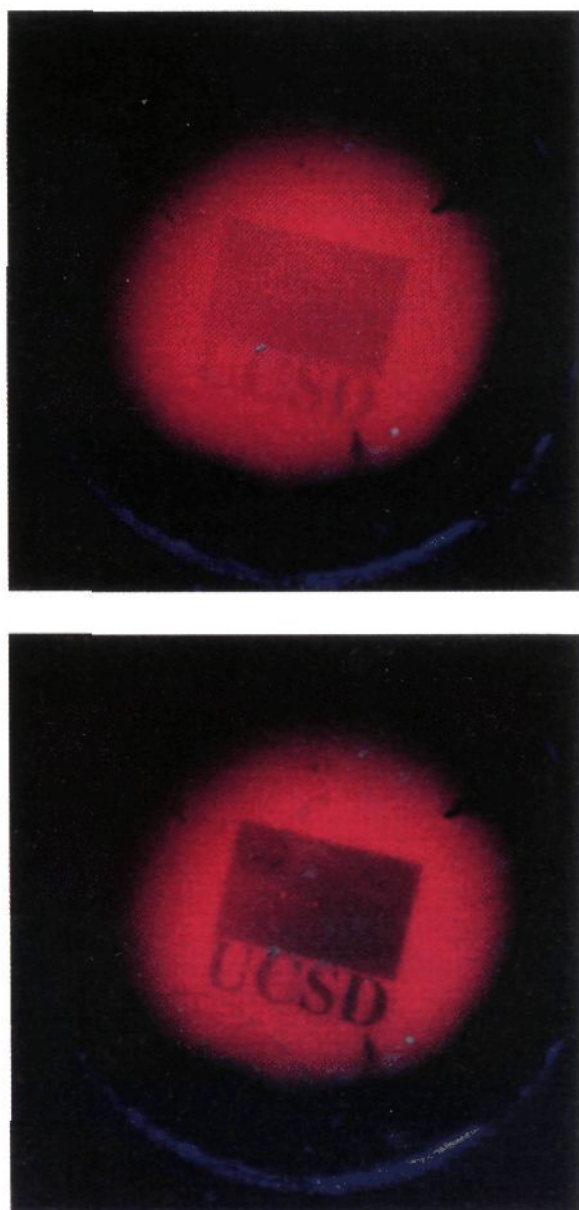
(4) Sheen, C. W.; Shi, J. X.; Martensson, J.; Parikh, A. N.; Allara, D. L. *J. Am. Chem. Soc.* **1992**, *114*, 1514.

(5) (a) Yang, H. C.; Aoki, K.; Hong, H. G.; Sackett, D. D.; Arendt, M. F.; Yau, S. L.; Bell, C. M.; Mallouk, T. E. *J. Am. Chem. Soc.* **1993**, *115*, 11855. (b) Shpeizer, B.; Poojary, D. M.; Ahn, K.; Runyan, C. E.; Clearfield, A. *Science* **1994**, *266*, 1357. (c) Katz, H. E. *Chem. Mater.* **1994**, *6*, 2227. (d) Thompson, M. E. *Chem. Mater.* **1994**, *6*, 1168.

(6) (a) Linford, M. R.; Fenter, P.; Eisenberger, P. M.; Chidsey, C. E. D. *J. Am. Chem. Soc.* **1995**, *117*, 3145. (b) Linford, M. R.; Chidsey, C. E. D. *J. Am. Chem. Soc.* **1993**, *115*, 12631.

(7) (a) Canham, L. T. *Appl. Phys. Lett.* **1990**, *57*, 1046. (b) Brus, L. E.; Szajowski, P. F.; Wilson, W. L.; Harris, T. D.; Schuppler, S.; Citrin, P. H. *J. Am. Chem. Soc.* **1995**, *117*, 2915. (c) Kavanagh, K. L.; Sailor, M. J. *Adv. Mater.* **1992**, *4*, 432. (d) Iyer, S. S.; Xie, Y. H. *Science* **1993**, *260*, 40.

(8) (a) Lavine, J. M.; Sawan, S. P.; Shieh, Y. T.; Bellezza, A. J. *Appl. Phys. Lett.* **1993**, *62*, 1099. (b) Anderson, R. C.; Muller, R. S.; Tobias, C. W. *J. Electrochem. Soc.* **1993**, *140*, 1393.



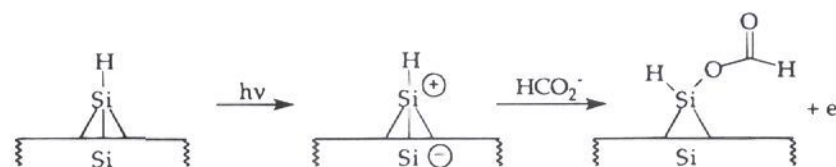
**Figure 2.** Photographs of the red PL (excitation with 365 nm light) from a circular (1 cm diameter) porous Si sample showing photopatterned square and lettering where the Si surface has been modified with silyl esters. Top (a): Sample in vacuum. The photopatterned square is somewhat discernible due to the lower PL quantum yield of the ester-modified porous silicon. Bottom (b): The same sample in the presence of H<sub>2</sub>O vapor. The intensity of emission from the nonderivatized Si–H surface is relatively unaffected by the water vapor (10–20% quenched). PL from the region patterned with the hydrophilic ester functionality is quenched by >60%.

Similarly, porous Si immersed in the formate electrolyte and illuminated at open circuit showed little or no sign of modification of the native Si–H surface. Thus the species observed on derivatized porous Si is not due to adsorbed formic acid or sodium formate. Formate bound to Si in a bidentate fashion can also be ruled out because such species would have  $\nu(\text{CO})$  stretches at a much lower energy and O–C–O symmetric and antisymmetric vibrational modes,<sup>2</sup> none of which were observed.

The single observed stretching mode indicates that the species is an ester, and the energy of the stretch falls within the range expected for silyl esters.

The integrated intensities of Si–H and OSi–H IR absorptions do not decrease after derivatization, indicating that the Si–ester bond is formed by breaking Si–Si bonds, Scheme 1.

#### Scheme 1



Porous Si can be photopatterned by illuminating the surface through a mask during the derivatization procedure. Photoluminescence (PL) from photopatterned surfaces is shown in the photographs in Figure 2. The photopatterned square and letters can be identified by their slightly lower emission intensity in Figure 2a. IR spectroscopy identified the less emissive area as that possessing the silyl ester surface.

It has previously been shown that the intensity of PL from porous Si is reversibly quenched by molecular adsorbates, and that the sensitivity can be tuned via surface modification.<sup>12,13</sup> In the present work, photoelectrochemical generation of the silyl ester surface rendered the porous Si PL susceptible to reversible quenching by H<sub>2</sub>O vapor. By comparison, PL from nonderivatized porous Si is quenched only slightly by H<sub>2</sub>O vapor due to the hydrophobic nature of the Si–H surface.<sup>12</sup> Thus the contrast between the derivatized and nonderivatized regions of Figure 2 increases upon exposure of the entire surface to water vapor (Figure 2b), relative to the sample in vacuum (Figure 2a). This work demonstrates photolithographic modification of a Si surface at the molecular level and the effect of such modification on properties such as carrier recombination rates and surface hydrophilicity.

**Acknowledgment.** This work was funded by the National Science Foundation. J.S.H. was supported by an NSF Research Experience for Undergraduates Fellowship.

**Supporting Information Available:** Detailed description of electrochemical experimental conditions, diagram of etch bath, IR spectra of a photopatterned sample, and emission spectra in vacuum and H<sub>2</sub>O vapor (4 pages). This material is contained in many libraries on microfiche, immediately follows this article in the microfilm version of the journal, can be ordered from the ACS, and can be downloaded from the Internet; see any current masthead page for ordering information and Internet access instructions.

JA951565B

(12) Lee, E. J.; Ha, J. S.; Sailor, M. J. In *Materials Research Society Symposium Proceedings: Microcrystalline and Nanocrystalline Semiconductors*; Collins, R. W., Tsai, C. C., Hirose, M., Koch, F., Brus, L., Eds.; MRS: Boston, MA, 1995; Vol. 358, pp 387–392.

(13) Lauerhaas, J. M.; Sailor, M. J. *Science* **1993**, *261*, 1567.